



Fabrication of copper objects through lithography-based metal manufacturing

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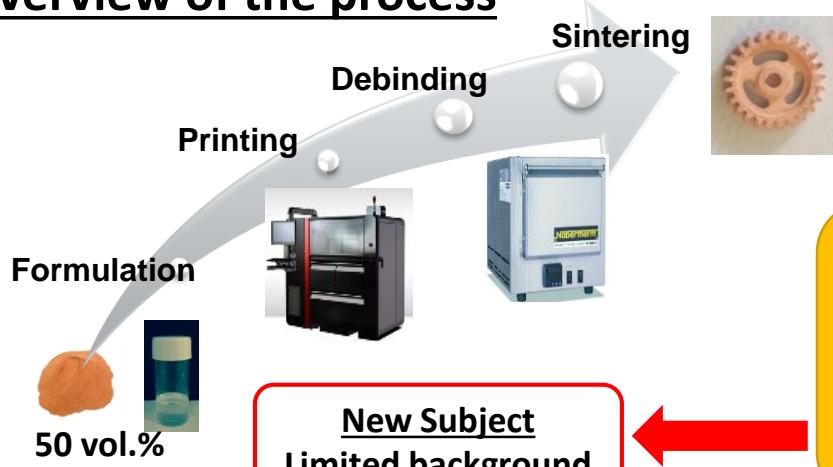
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Overview of the process



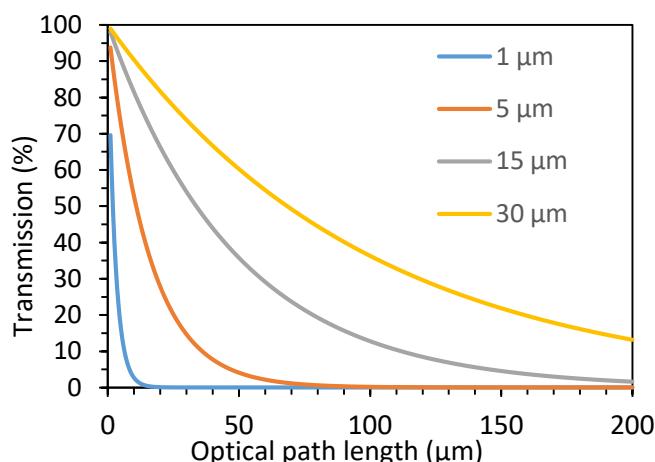
Main strengths :

- High 3D resolution
- New geometries affordable

Main issues :

- High UV absorption of copper particles at 365 nm : limitation of printed thickness
- High thermal & electrical conductivities
 - High loading rate
 - Low C/O contaminations
 - Part integrity

Modeling of UV transmission in a layer according Mie's theory



$$T = \exp(-N \times l \times \sigma_{ext})$$

σ_{ext} : extinction cross section (m^{-2})

N : Particle concentration (ptcl. m^{-3})

l : optical path length (m)

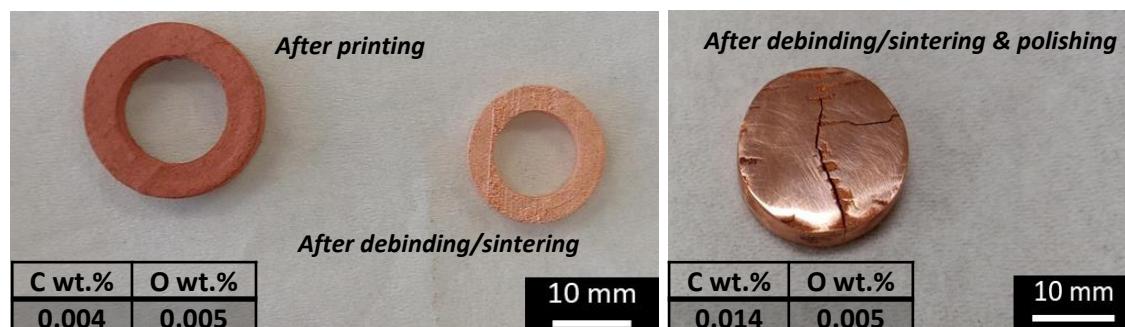
45 wt.% (=10 vol.%) @ 365 nm

Large particle diameter

→ enables a high depth penetration of light

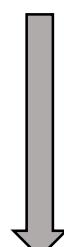
Printing and thermal treatments of the first objects

Part for characterization



Conclusions

- ✓ Printing copper parts by LMM with a high loading rate
- ✓ Low C&O contents → no impact on conductivities
- ✓ Part integrity achieved with wall thickness < 2mm



Perspectives

Achievement of crack free objets for characterizations (thermal & electrical conductivities)

• ↴ polymer crosslinking density

• optimized thermal debinding